

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Trung T. Doan
Title: CHEMICAL DISPENSING SYSTEM FOR SEMICONDUCTOR WAFER PROCESSING

Docket No.: 303.928US5
Filed: August 31, 2000
Examiner: Sylvia MacArthur

Serial No.: 09/652,713
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Group Art Unit: 1763

MS AF


Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

We are transmitting herewith the following attached items (as indicated with an "X"):

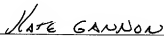
☒ Amendment and Response Under 37 CFR 1.116 (7 pgs.).

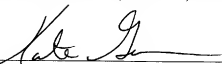
If not provided for in a separate paper filed herewith, Please consider this a PETITION FOR EXTENSION OF TIME for sufficient number of months to enter these papers and please charge any additional fees or credit overpayment to Deposit Account No. 19-0743.

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.
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By: 
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CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence is being filed using the USPTO's electronic filing system EFS-Web, and is addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this 19 day of March, 2007.


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(GENERAL)